



2125 JFW

In re Application of:

Docket No. 00862.022239

SHIGEYUKI UZAWA, ET AL.

Application No.: 09/864,309

Examiner: Ryan A. Jarrett

Filed: May 25, 2001

Group Art Unit: 2125

For: EXPOSURE APPARATUS, COATING/  
DEVELOPING SYSTEM, DEVICE  
MANUFACTURING SYSTEM, DEVICE  
MANUFACTURING METHOD,  
SEMICONDUCTOR MANUFACTURING  
FACTORY, AND EXPOSURE APPARATUS  
MAINTENANCE METHOD

November 10, 2004

**Mail Stop Amendment**

Commissioner For Patents

P.O. Box 1450

Alexandria, Virginia 22313-1450

Sir:

Transmitted herewith is an Amendment in the above-identified application.

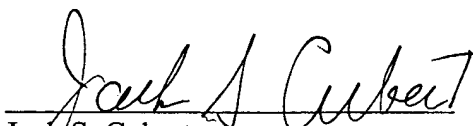
☒ No additional fee is required.

The fee has been calculated as shown below:

| CLAIMS AS AMENDED                             |  |       |  |                         |                |                   |
|---|--|-------|--|-------------------------|----------------|-------------------|
|   | (2)<br>CLAIMS<br>REMAINING<br>AFTER<br>AMENDMENT |       | (4)<br>HIGHEST NO.<br>PREVIOUSLY<br>PAID FOR | (5)<br>PRESENT<br>EXTRA | RATE           | ADDITIONAL<br>FEE |
| TOTAL<br>CLAIMS                               | 14   | MINUS | 47   | =<br>0                  | x \$9<br>\$18  | 0.00              |
| INDEP.<br>CLAIMS                              | 1  | MINUS | 9  | =<br>0                  | x \$43<br>\$88 | 0.00              |
| Fee for Multiple Dependent claims \$150/\$300 |  |       |  |                         |                | 0.00              |
| TOTAL ADDITIONAL FEE<br>FOR THIS AMENDMENT--- |  |       |  |                         |                | 0.00              |

- ☐ °Verified Statement claiming small entity status is enclosed, if not filed previously.
- ☐ A check in the amount of \$\_\_\_\_ is enclosed.
- ☐ Charge \$\_\_\_\_ to Deposit Account No. 06-1205. A duplicate copy of this sheet is enclosed.
- ☒ Any prior general authorization to charge an issue fee under 37 C.F.R. 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 C.F.R. 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate copy of this paper is enclosed.
- ☐ A check in the amount of \$\_\_\_\_ to cover the fee for a \_\_\_\_ month extension is enclosed.
- ☐ A check in the amount of \$\_\_\_\_ to cover the Information Disclosure Statement fee is enclosed.
- ☒ Applicants' attorney, Steven E. Warner, may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,

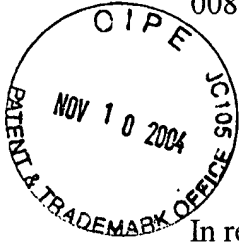
  
\_\_\_\_\_  
Jack S. Cubert  
Attorney for Applicants  
Registration No. 24,245

FITZPATRICK, CELLA, HARPER & SCINTO  
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New York, New York 10112-3800  
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SEW/JSC/dc

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00862.022239

PATENT APPLICATION



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
: Examiner: Ryan A. Jarrett  
SHIGEYUKI UZAWA, ET AL. )  
: Group Art Unit: 2125  
Application No.: 09/864,309 )  
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Filed: May 25, 2001 )  
:  
For: EXPOSURE APPARATUS, )  
COATING/DEVELOPING SYSTEM :  
DEVICE MANUFACTURING SYSTEM, )  
DEVICE MANUFACTURING METHOD, :  
SEMICONDUCTOR MANUFACTURING )  
FACTORY, AND EXPOSURE :  
APPARATUS MAINTENANCE METHOD) November 10, 2004

**Mail Stop Amendment**  
COMMISSIONER FOR PATENTS  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

AMENDMENT

Sir:

In response to the Office Action dated August 10, 2004, please amend the above  
identified application as follows: